

OPTI 415/515 Overview

OPTI 415/515 is an engineering course that is designed to unite concepts from several geometrical and physical optics courses. The goal of the class is to provide understanding of the requirements for specifying optical elements, fabricating the parts and evaluating the performance of the delivered part.

Course Web Site

<http://www.visualopticslab.com/OPTI515R/OPTI515R.html>

Tests (Open Notes)

Midterm 1	February 23, 2012 in class, open notes
Midterm 2	April 5, 2012 in class, open notes
Final	May 8, 2012 10:30 am -12:30pm

Grading

Undergraduate/Graduate (Graduate students will have additional problems assigned)

Homeworks	25% (approximately 8-10 homeworks)
Midterm 1	25%
Midterm 2	25%
Final Exam	25%

Teaching Assistant

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Office Hours: TBD

Suggested References

Fischer RE, Tadic-Galeb B, Yoder PR. *Optical System Design, 2nd ed.* (Mcgraw-Hill, New York, 2008).

Malacara D. *Optical Shop Testing, 3rd ed.* (Wiley, New Jersey, 2007).

Smith W. *Modern Optical Engineering, 4th ed.* (Mcgraw-Hill, New York, 2008).

Draft Outline

1. Properties of Optical Systems
 - 1.1. Optical Properties of a Single Spherical Surface (Brief Review)
 - 1.1.1. Refractive Surface: Radius, Curvature, Focal Length and Power
 - 1.1.2. Reflective Surface: Focal Length and Power
 - 1.1.3. Gaussian Imaging Equation
 - 1.1.4. Newton's Equation
 - 1.2. Aperture and Field Stops (Brief Review)
 - 1.2.1. Aperture Stop Definition
 - 1.2.2. Marginal Ray
 - 1.2.3. Chief Ray
 - 1.2.4. Vignetting
 - 1.2.5. Field Stop Definition
 - 1.2.5.1. Image Sensor as Field Stop
 - 1.2.5.1.1. Standard CCD/CMOS sensor dimensions
 - 1.3. First Order Properties of an Optical System (Brief Review)
 - 1.3.1. Gaussian Reduction (Conceptually)
 - 1.3.2. ynu raytrace
 - 1.3.3. Cardinal Points
 - 1.3.4. Entrance and Exit Pupils
 - 1.3.5. Extension of Gaussian Imaging to Thick Systems
 - 1.3.6. Transverse and Longitudinal Magnification
 - 1.3.7. Lagrange invariant, Etendue, Throughput, $A\Omega$ Product
 - 1.3.8. F-Number, Working F-Number and Numerical Aperture
 - 1.3.9. Depth of Field
 - 1.3.10. Field of View
 - 1.3.11. Front and Back Focal Distances
 - 1.3.11.1. Standard Flange distances for cameras
 - 1.4. Measurement of First Order Properties of Optical Systems
 - 1.4.1. Measurements based on Gaussian Imaging Equation
 - 1.4.2. Autocollimation Technique
 - 1.4.3. Neutralization Test
 - 1.4.4. Focimeter
 - 1.4.5. Focal Collimator
 - 1.4.6. Reciprocal Magnification
 - 1.4.7. Nodal-Slide Lens Bench
 - 1.5. Diffraction and Aberrations
 - 1.5.1. Black Box Optical System based on Cardinal Points and Pupils.
 - 1.5.2. Wavefront Picture of Optical Imaging
 - 1.5.3. Diffraction-Limited Systems and Connection to Fresnel Diffraction
 - 1.5.4. Point Spread Function (PSF) calculation and dimensions
 - 1.5.5. Sign and Coordinate System Conventions
 - 1.5.6. Optical Path Length (OPL), Optical Path Difference (OPD), Wavefront Error
 - 1.5.7. Transverse Ray Error and Spot Diagrams
 - 1.5.8. Aberrations of Rotationally Symmetric Optical Systems
 - 1.5.8.1. Piston and Tilt

- 1.5.8.2. Seidel Aberrations
- 1.5.9. Aberrations of General Optical Systems
 - 1.5.9.1. Examples of non-rotationally symmetric systems
 - 1.5.9.2. Generalization of Seidel Aberrations to on-axis case
 - 1.5.9.3. Zernike polynomials
 - 1.5.9.3.1. Different variations found in literature
 - 1.5.9.3.2. Normalization, Radial Polynomials, Azimuthal components
 - 1.5.9.3.3. Examples of different orders of Zernike polynomials
 - 1.5.9.3.4. Representation of complex wavefront as linear combination
 - 1.5.9.3.5. Coordinate system conversions
 - 1.5.9.3.6. Pupil Size Conversion
 - 1.5.9.3.7. Fitting wavefront error to Zernike polynomials
- 1.5.10. Through-Focus PSF and Star Test
 - 1.5.10.1. Diffraction Limited Case (Defocus)
 - 1.5.10.2. Seidel Spherical Aberration
 - 1.5.10.3. Zernike Spherical Aberration
 - 1.5.10.4. Astigmatism
 - 1.5.10.5. Coma
- 1.5.11. Measurement of Distortion
 - 1.5.11.1. Conventional case
 - 1.5.11.2. Special Cases anamorphic, $f\theta$ lens. Scheimpflug
- 1.6. Optical Quality Metrics
 - 1.6.1. Resolution Targets
 - 1.6.1.1. Rayleigh Criterion
 - 1.6.2. Strehl Ratio
 - 1.6.3. Peak-to-Valley and rms Wavefront Error
 - 1.6.3.1. Relationship to Zernike Coefficients
 - 1.6.3.2. Relationship to Strehl Ratio
 - 1.6.4. Encircled and Ensquared Energy
 - 1.6.5. Optical Transfer Function (OTF)
 - 1.6.5.1. Modulation Transfer Function (MTF)
 - 1.6.5.2. Phase Transfer Function (PTF)
 - 1.6.5.3. Fourier Transform relationship to PSF
 - 1.6.5.4. Autocorrelation of Pupil Function
 - 1.6.5.5. Line Spread Function
 - 1.6.5.6. Siemens Star
- 1.7. Aspheric Surfaces
 - 1.7.1. Conics
 - 1.7.2. Quadrics
 - 1.7.3. Higher Order Aspheres
 - 1.7.4. Torics
 - 1.7.5. Cylinders
- 2. Fabrication of Optical Surfaces
 - 2.1. Optical Materials
 - 2.1.1. Glass and Plastics
 - 2.1.2. Cauchy and Sellmeier Equations

- 2.1.3. Infrared and Ultraviolet Materials
- 2.2. Grinding and Polishing Flats, Windows and Prisms
- 2.3. Grinding and Polishing Spherical Surfaces
- 2.4. Grinding and Polishing Aspheric Surfaces
- 2.5. Diamond Turning and Fast Tool Servo
- 2.6. Magnetorheological Finishing
- 3. Non-interferometric Testing
 - 3.1. Autocollimator Tests
 - 3.2. Surface Radius of Curvature
 - 3.2.1. Geneva Gauge
 - 3.2.2. Spherometer
 - 3.2.3. Autostigmatic measurements
 - 3.3. Wavefronts
 - 3.3.1. Foucault Knife Edge Test
 - 3.3.2. Wire Test
 - 3.3.3. Ronchi Test
 - 3.3.4. Hartmann Screen Test
 - 3.3.5. Shack-Hartmann Sensor
 - 3.3.5.1. Fitting Shack-Hartmann Data to Zernike polynomials
- 4. Basic Interferometry and Optical Testing
 - 4.1. Review of Two Beam Interference
 - 4.1.1. Plane waves
 - 4.1.2. Spherical waves
 - 4.1.3. General wavefront shapes
 - 4.1.4. Visibility
 - 4.1.5. Coherence and Polarization
 - 4.2. Newton's Rings
 - 4.2.1. Patterns
 - 4.2.2. Determining convexity
 - 4.2.3. Test Plates
 - 4.3. Fizeau Interferometer
 - 4.3.1. Classical Fizeau
 - 4.3.2. Configurations for Flats, Concave and Convex Surfaces
 - 4.3.3. Laser Fizeau
 - 4.4. Twyman-Green Interferometer
 - 4.4.1. Common Configurations
 - 4.5. Mach-Zehnder Interferometer
 - 4.5.1. Common Configurations
 - 4.5.2. Single Pass
 - 4.6. Lateral Shearing Interferometers
 - 4.6.1. Common Configurations
 - 4.6.2. Derivatives of wavefronts
 - 4.7. Interferograms
 - 4.7.1. Seidel Aberrations
 - 4.8. Phase-Shifting Interferometry
 - 4.8.1. Phase Shifters

- 4.8.2. Algorithms
 - 4.8.3. Phase unwrapping
 - 4.8.4. Calibration and errors
- 4.9. Testing Aspheric Surfaces
 - 4.9.1. Computer Generated Holograms
- 5. Optical Specification
 - 5.1. ISO 1101 Standard
 - 5.2. ISO 10110 Standard
 - 5.2.1. General
 - 5.2.2. Stress Birefringence
 - 5.2.3. Bubbles and Inclusions
 - 5.2.4. Homogeneity
 - 5.2.5. Surface Form Errors
 - 5.2.6. Centering
 - 5.2.7. Surface Imperfections
 - 5.2.8. Texture
 - 5.2.9. Surface Treatment and Coatings
 - 5.2.10. Tables for Elements and Assemblies
 - 5.2.11. Non-toleranced Data
 - 5.2.12. Aspheric Surfaces
 - 5.2.13. Wavefront Deformation
 - 5.2.14. Laser Damage Threshold